

제20회 한국반도체학술대회

2013년 2월 4일(월)~6일(수) / 웰리힐리파크 (구, 성우리조트)

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K. Memory (Design & Process Technology) 분과

Room E

스타홀 (본관, 2층)

2013년 2월 6일(수) 15:10-16:25

[WE3-K] Nonvolatile Memory Techniques II

좌장: 곽동화(삼성전자), 김용기(SK 하이닉스)

[초청]

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|---------|-------------|--|
| WE3-K-1 | 15:10-15:40 | Challenge in Development of Resistance Switching Memory
김수길, 정수옥, 이정훈, 홍성주
SK 하이닉스 연구소 선행소자그룹 선행소자Nt팀 |
| WE3-K-2 | 15:40-15:55 | Analysis of Stress-Induced Traps Generation on Random Telegraph Noise for TANOS(TaN-Al₂O₃-Si₃N₄-SiO₂-Si) NAND Flash Memories
Byeong-In Choe ^{1,2} , Changseok Kang ² , Youngwoo Park ² , Woonkyung Lee ² ,
Byung-Gook Park ¹ , and Jong-Ho Lee ¹
¹ School of EECS and ISRC, Seoul National University, ² Flash TD,
Semiconductor R&D Center, Samsung Electronics Co., Ltd. |
| WE3-K-3 | 15:55-16:10 | Channel Selection by Multi Level Operation of String Select Line in 3D Channel Stacked NAND Flash Memory Array
Wandong Kim, Yoon Kim, Se-Hwan Park, Joo Yun Seo, Do-Bin Kim, Sang-Ho Lee, and Byung-Gook Park
Inter-University Semiconductor Research Center and School of Electrical Engineering and Computer Science, Seoul National University |
| WE3-K-4 | 16:10-16:25 | Relationship between Program Disturb and Initial Erase State for Endurance in NAND Flash Memory
윤중호, 홍옥천, 김홍식, 우형동, 유원정, 장성진, 김영삼, 박성욱, 김건수, 이규필
삼성전자 제조센터 Yield Enhancement Team |